

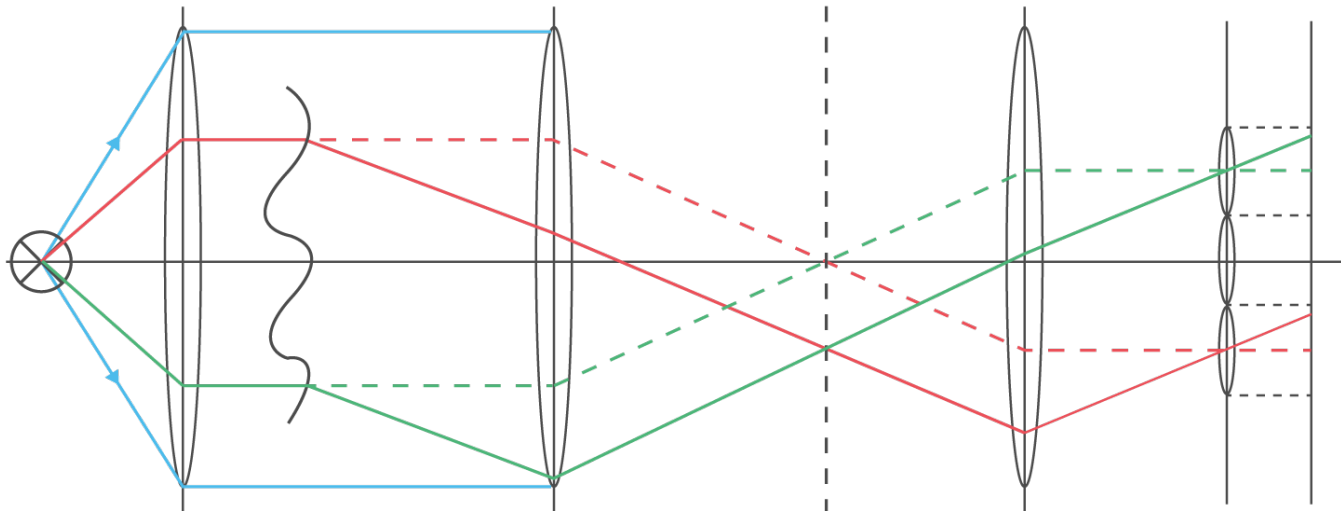
Light Field Methods for the Visual Inspection of Transparent Objects

UC Louvain, Image and Signal Processing Seminars - 2017

Johannes Meyer

Department of Informatics – Institute for Anthropomatics and Robotics – Vision and Fusion Laboratory

Fraunhofer-Institute of System Technologies, Optronics and Image Exploitation – Department of Visual Inspection Systems

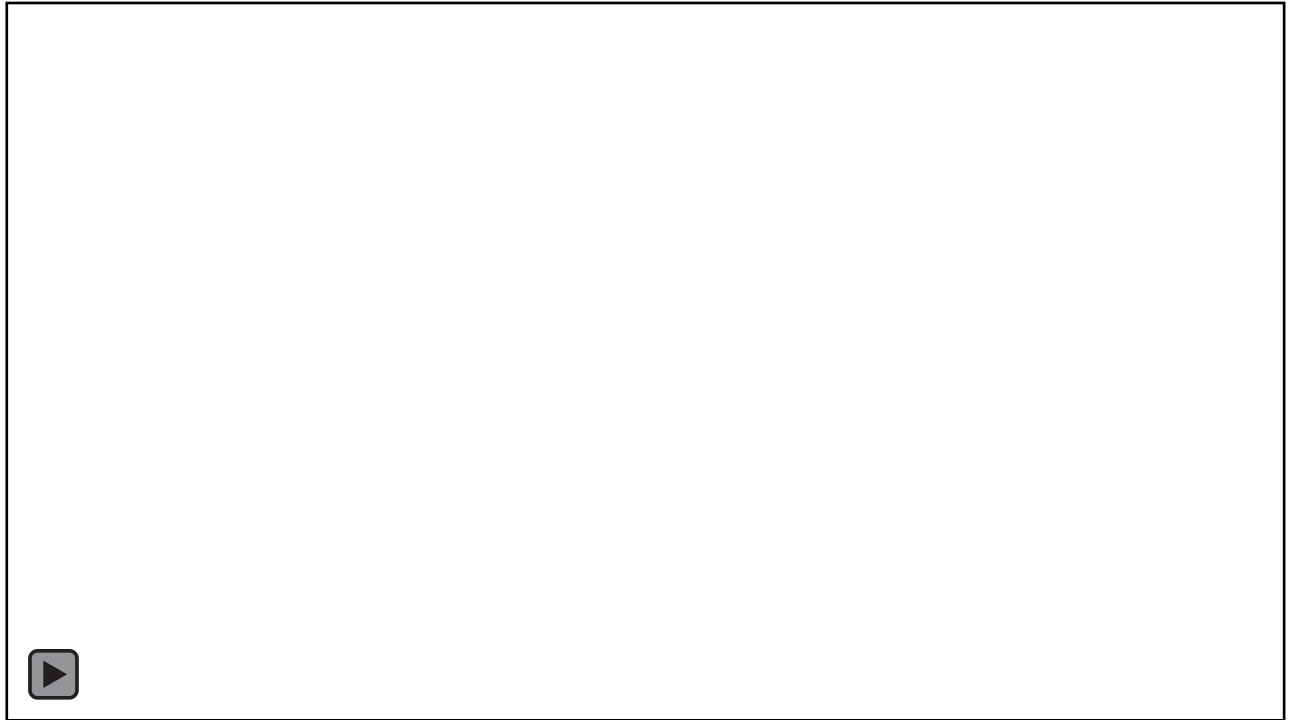
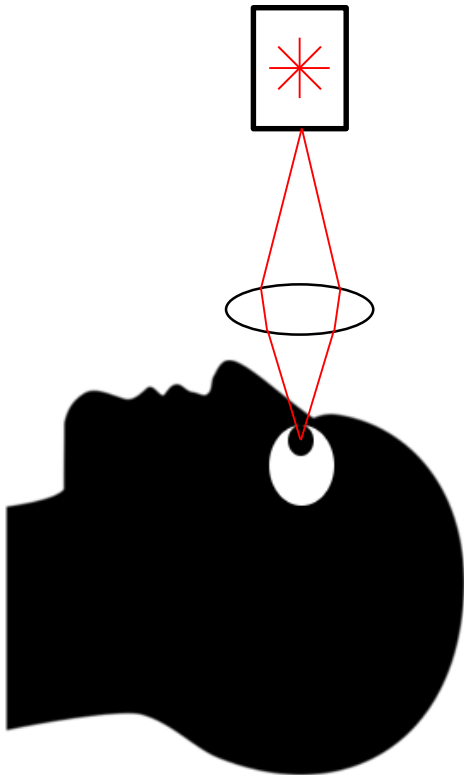


Motivation and Introduction

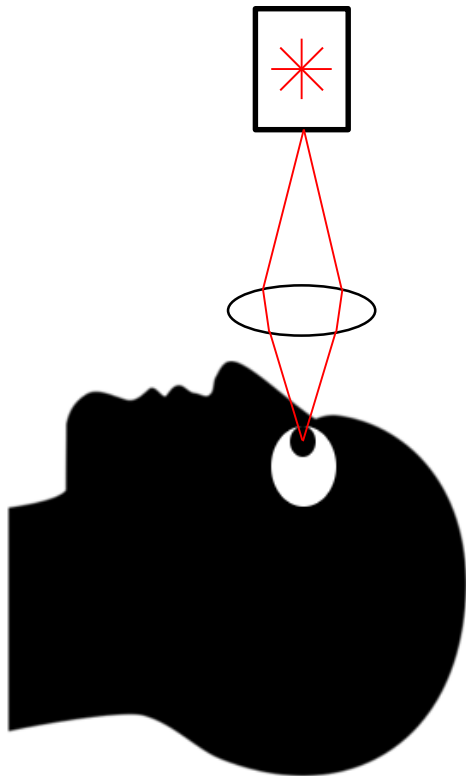
- Why bother about transparent object inspection?
- Transparent objects are massively used in diverse industries and need to meet highest quality requirements.



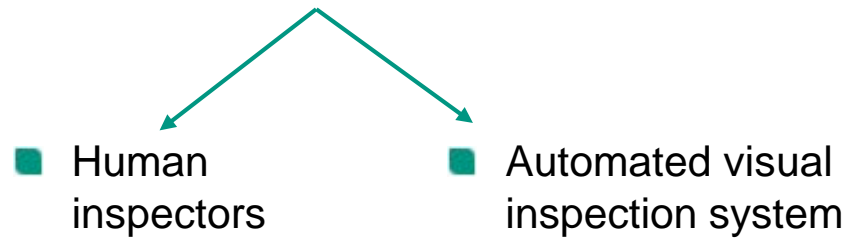
Motivation and Introduction



Motivation and Introduction



- Quality control indispensable

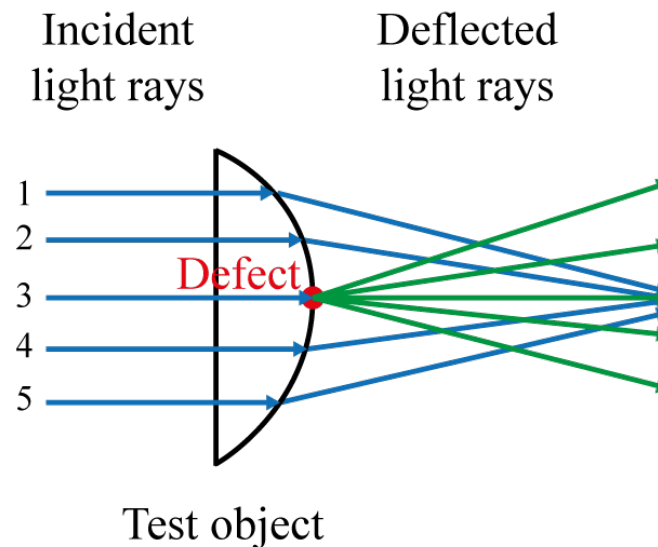


- Important types of defects:

- Opaque inclusions
- Transparent, scattering inclusions

Motivation and Introduction

- Why use light fields?



- Because for some important kinds of material defects, the information about their presence is conveyed by the light's propagation direction.

Motivation and Introduction

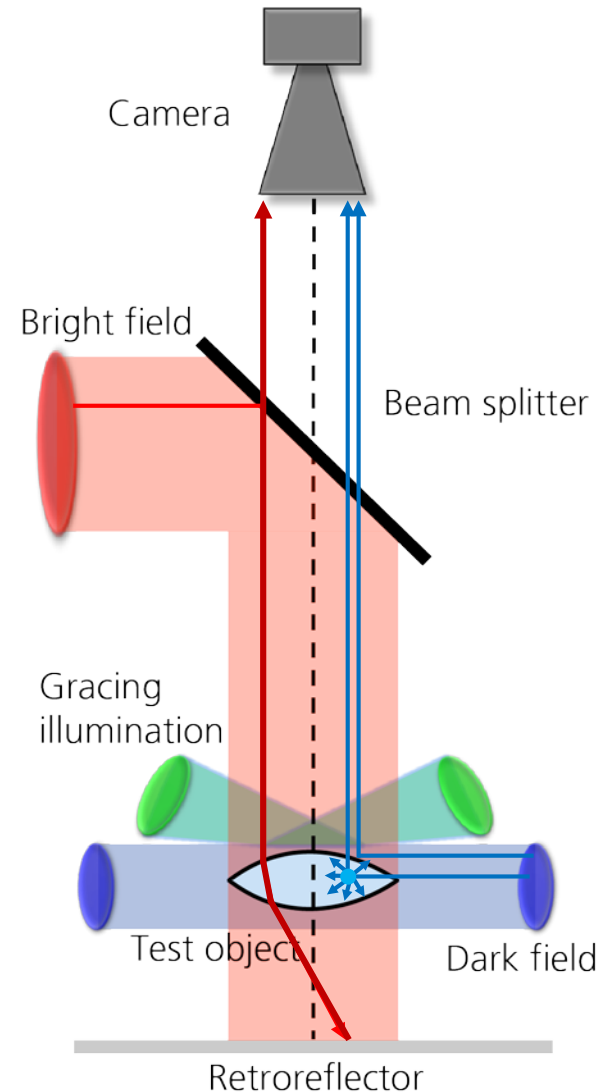
- Why am I here?
 - We will come to that ... 😊

Outline

- State of the Art
- Light Field Methods
 - Basic Idea
 - Deflection Maps
 - Acquisition
 - Processing
 - Inverse Light Field Illumination
- Summary & Outlook

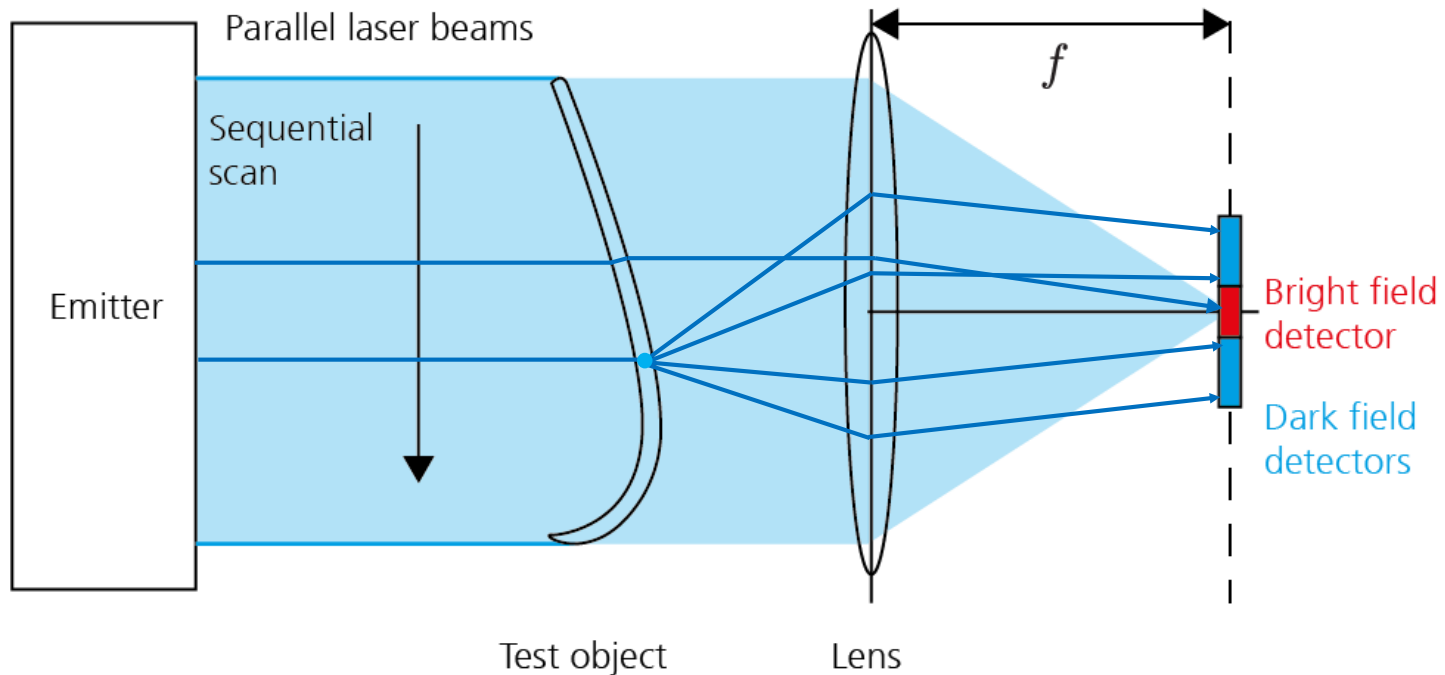
State of the Art

- Purity
a multi channel inspection system
- Bright field (red channel)
Opaque contaminants ✓
- Dark field
(blue & green channels):
Transparent, scattering
inclusions & scattering surface defects ✓
- Problem:
 - Requires well-designed
arrangement and placement of light
sources in order to avoid reflections.



State of the Art

■ Laser scanner system Purity

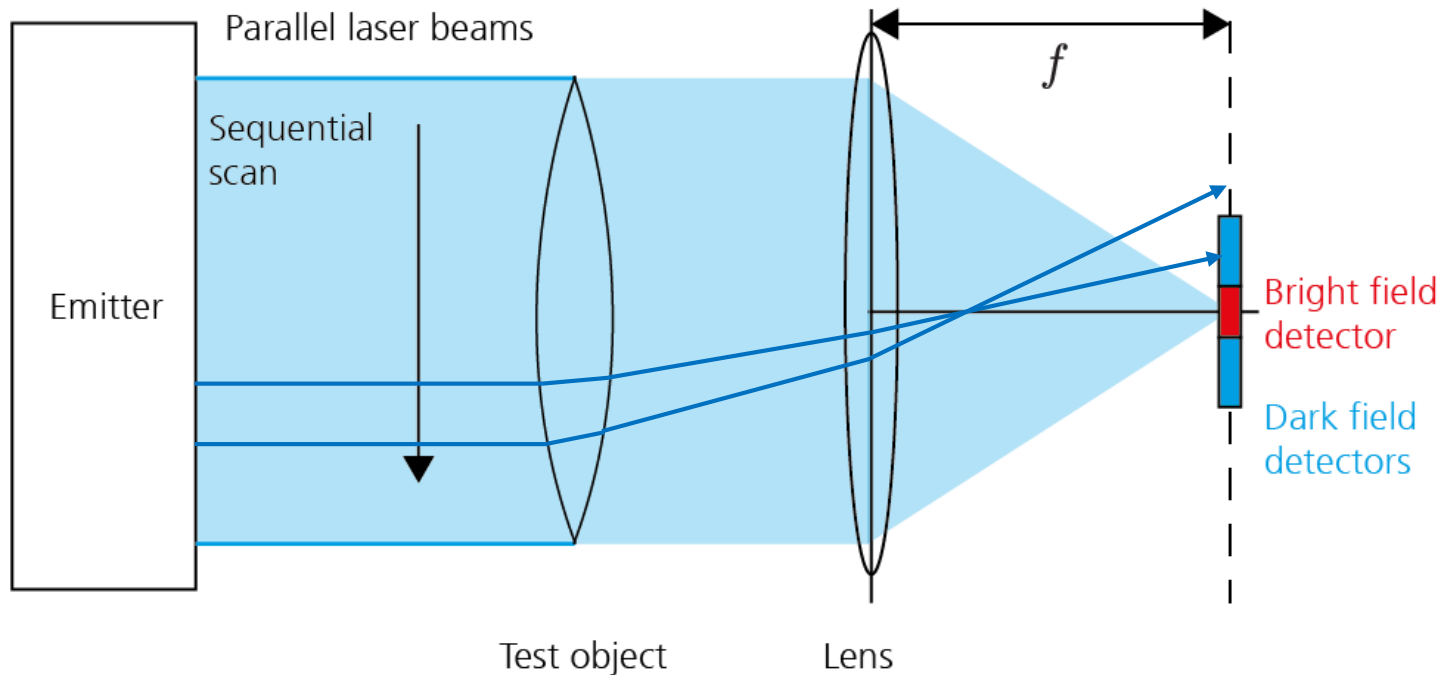


■ Bright field channel: opaque inclusions ✓

■ Dark field channel: transparent, scattering inclusions ✓

State of the Art

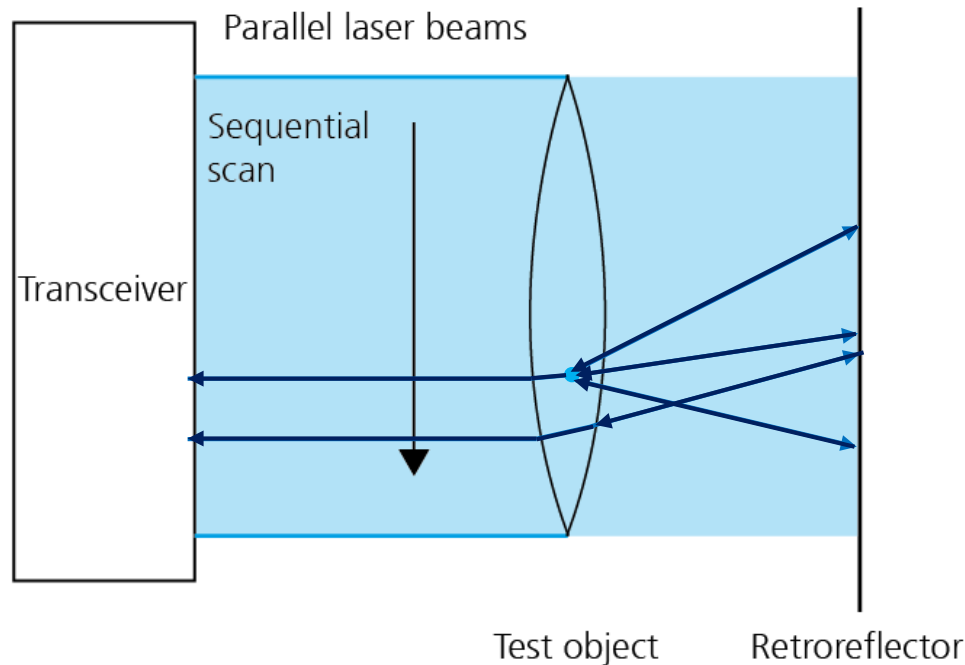
- Laser scanner system Purity – uncooperative test object



- Ray deflections caused by the test object's more complex geometry
 - ➔ False signals captured by the dark field detectors
 - ➔ Dark field detectors missed at all

State of the Art

■ Laser scanner system Purity with retroreflector



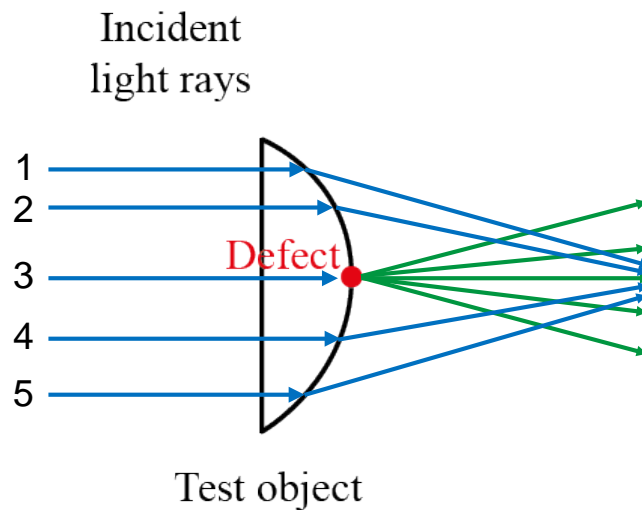
■ Retroreflector

- + mitigates influence of the test object's geometry
→ visualization of opaque defects
- compensates deflections caused by scattering defects
→ scattering defects are **not** visualized



Light Field Methods

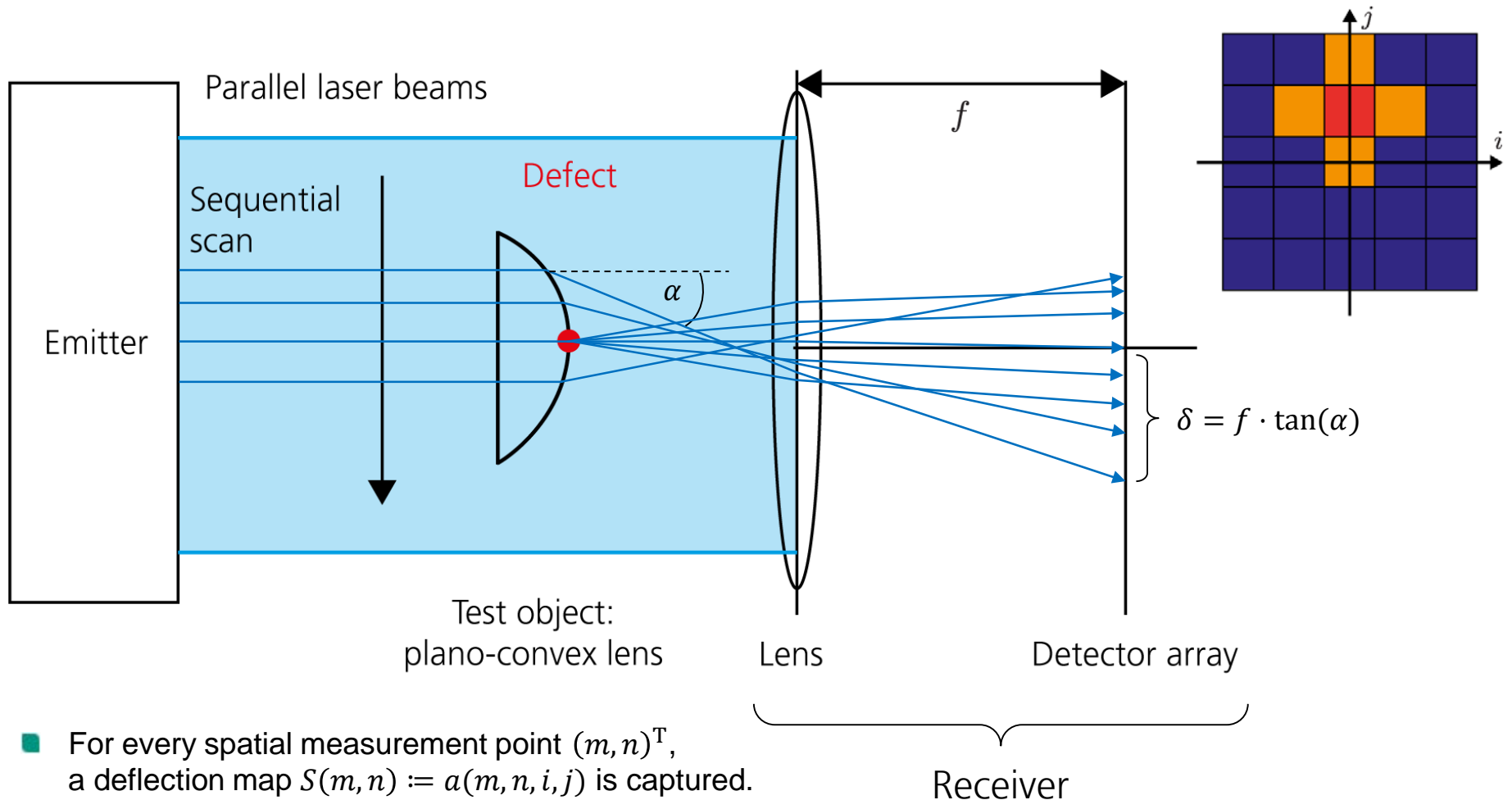
- Basic ideas – consider a test object with a scattering defect



- 4D-Light field $\mathcal{L}(x, y, \theta, \varphi)$ contains the information for defect detection.

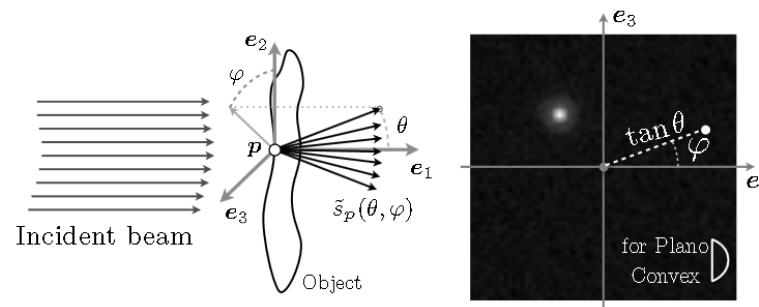
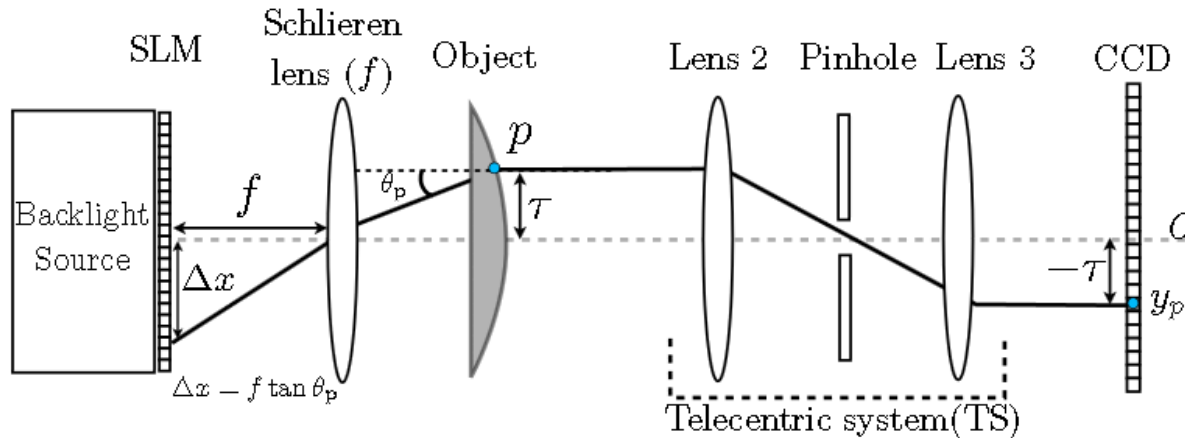
Light Field Methods – Deflection Map Acquisition

- Acquisition of deflection maps using a laser deflection scanner



Light Field Methods – Deflection Map Acquisition

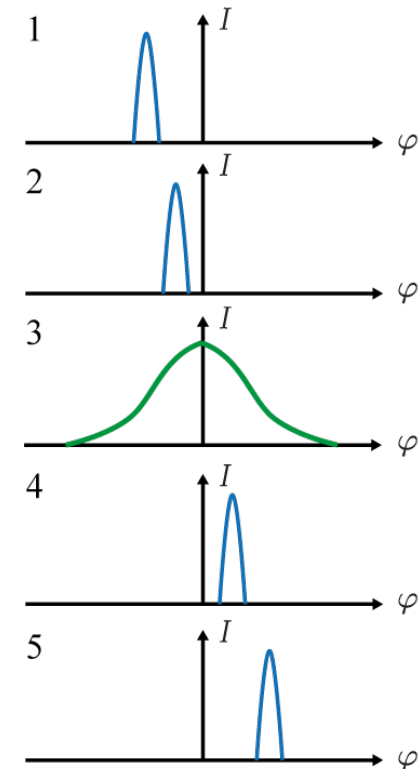
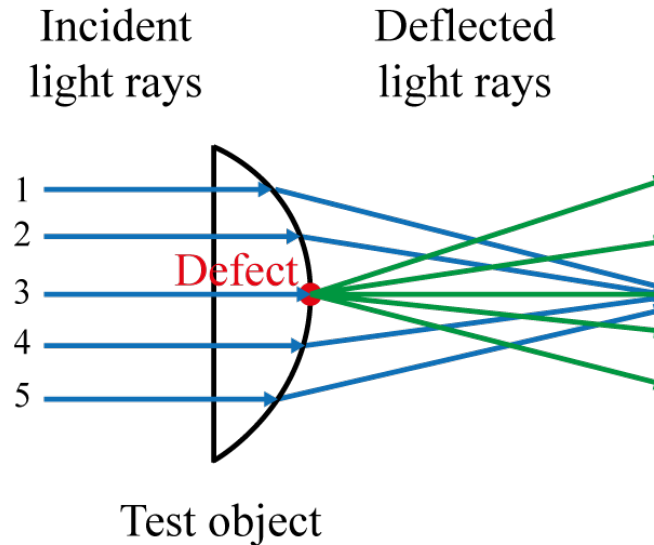
- Deflection maps... sounds familiar?



- Sudhakar, P., Jacques, L., Dubois, X., Antoine, P., & Joannes, L. (2015). Compressive imaging and characterization of sparse light deflection maps. *SIAM Journal on Imaging Sciences*, 8(3), 1824-1856.

Light Field Methods – Deflection Maps

- Processing:
Scattering defects →
Discontinuities between
spatially adjacent
deflection maps



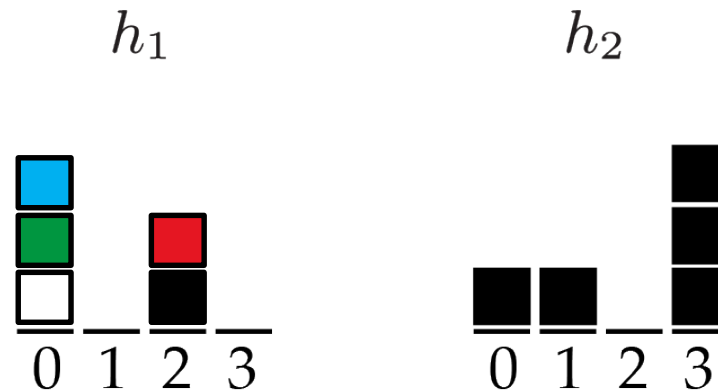
- Gradient Δ_S of S :

$$\Delta_S(m, n) = \begin{pmatrix} d(S(m-1, n), S(m+1, n)) \\ d(S(m, n-1), S(m, n+1)) \end{pmatrix}$$

- Search for defects in $\|\Delta_S\|$ using common image processing methods.
- Which distance $d(\cdot, \cdot)$ to choose? → Histogram distances!

Light Field Methods – Deflection Map Processing

- Possible choice for $d(\cdot, \cdot)$: Earth Mover's Distance $EMD(\cdot, \cdot)$
 - Distance measure between two histograms h_1, h_2 .
 - $EMD(h_1, h_2) \approx$ minimal transformation costs between h_1 and h_2 .
 - Example for 1D-EMD:



$$EMD(h_1, h_2) = 1 + 1 + 3 + 1 = 6$$

Light Field Methods – Deflection Map Processing

- Generalized Cramér-von Mises Distance

- Main ingredient: Localized Cumulative Distribution (LCD)
- Random vector $\tilde{\mathbf{x}} \in \mathbb{R}^N$, $N \in \mathbb{N}$ with probability density function $f: \mathbb{R}^N \rightarrow \mathbb{R}_+$
→ cumulative distribution not well-defined
- Hanebeck et al. introduced well-defined LCD $F(\mathbf{x}, \mathbf{b})$:

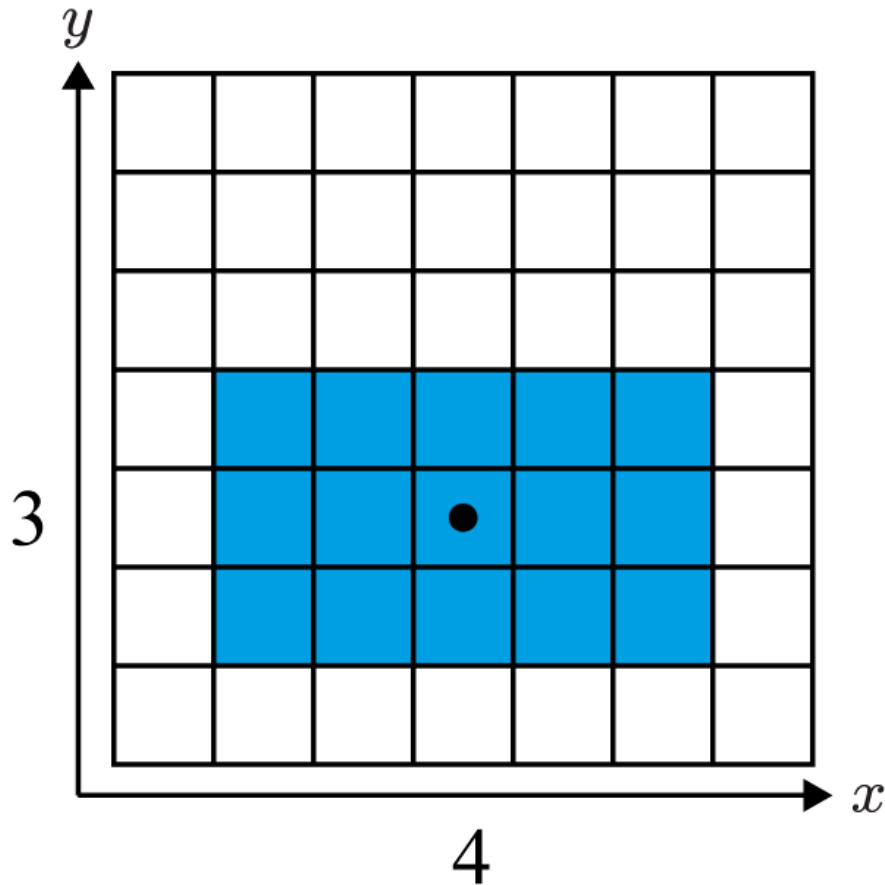
$$F(\mathbf{x}, \mathbf{b}) = \int_{\mathbf{x}-\mathbf{b}}^{\mathbf{x}+\mathbf{b}} f(\mathbf{t}) d\mathbf{t}$$

- LCD is kind of an integral transform with kernel \mathbf{b} .

Hanebeck, Uwe D., and Vesa Klumpp. "Localized cumulative distributions and a multivariate generalization of the Cramér-von Mises distance." *Multisensor Fusion and Integration for Intelligent Systems, 2008. MFI 2008. IEEE International Conference on.* IEEE, 2008.

Light Field Methods – Deflection Map Processing

- Generalized Cramér-von Mises Distance
 - Main ingredient: Localized Cumulative Distribution (LCD)



$$F \left((4, 3)^T, (2, 1)^T \right)$$

Hanebeck
cramér-v
MFI 2008. IEEE International Conference on IEEE, 2008.

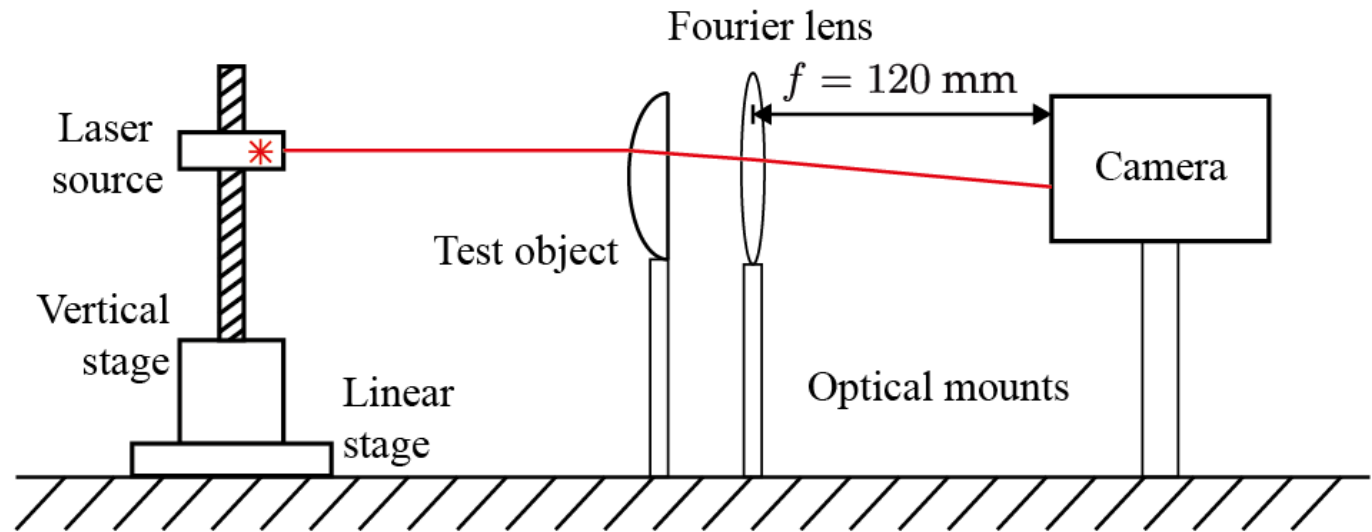
Light Field Methods – Deflection Map Processing

- For two random vectors $\tilde{\mathbf{x}}, \tilde{\mathbf{y}} \in \mathbb{R}^N, N \in \mathbb{N}$ with probability density functions $f(\mathbf{x}), g(\mathbf{x})$ and their LCDs $F(\mathbf{x}, \mathbf{b}), G(\mathbf{x}, \mathbf{b})$, the generalized Cramér-von Mises distance is defined as:

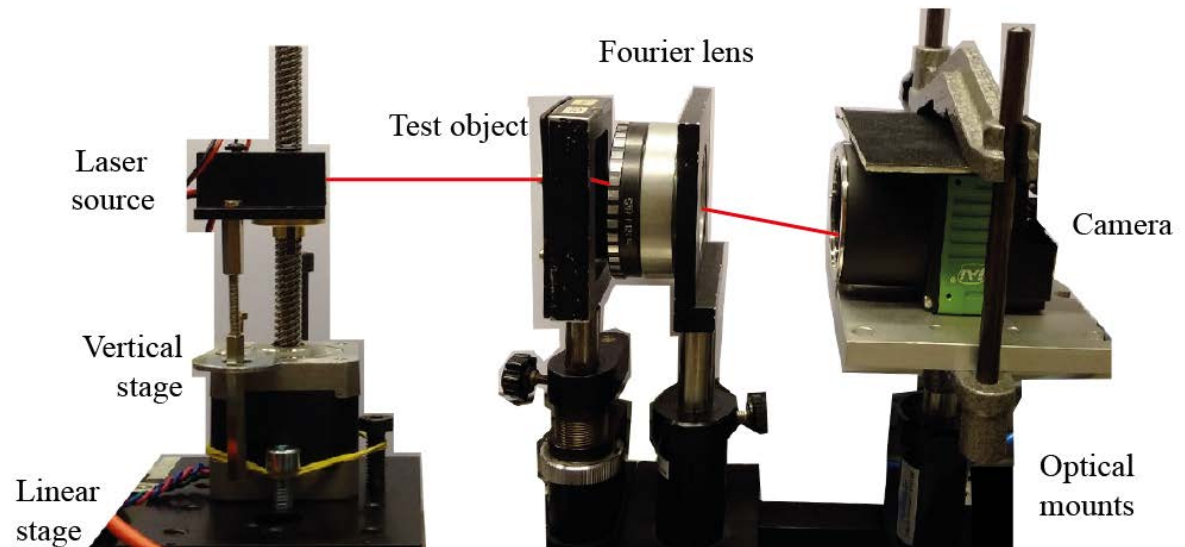
$$D(f, g) = \int_{\mathbb{R}^N} \int_{\mathbb{R}_+^N} (F(\mathbf{x}, \mathbf{b}) - G(\mathbf{x}, \mathbf{b}))^2 d\mathbf{b} d\mathbf{x}$$

Light Field Methods – Deflection Map Processing

- Design of a first prototype:



- Realization:

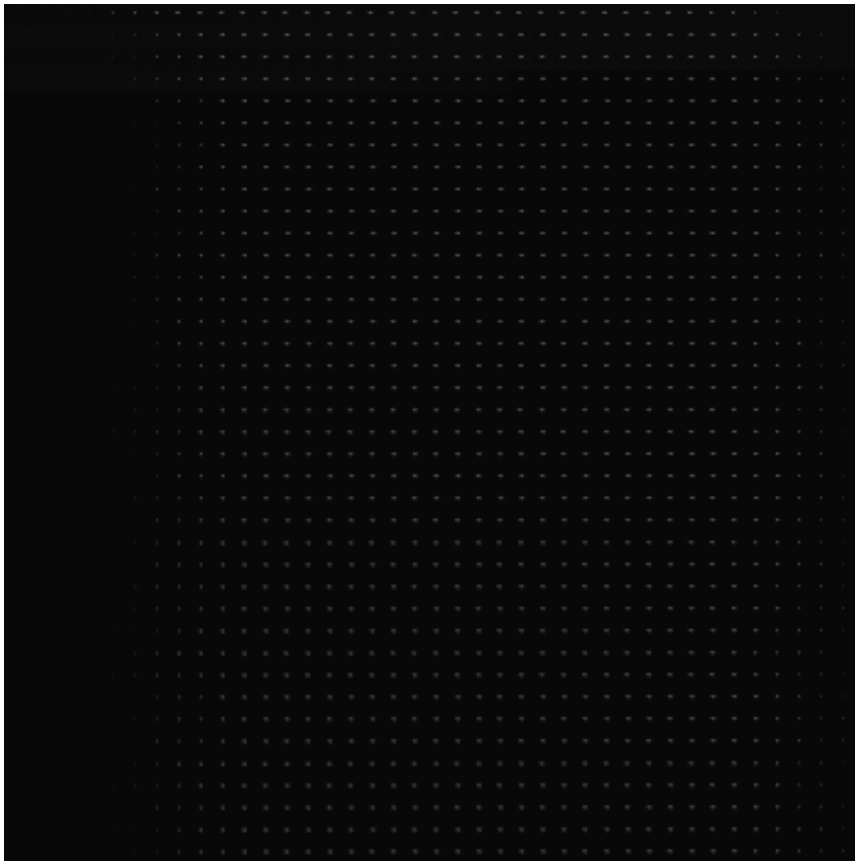


Light Field Methods – Deflection Map Processing

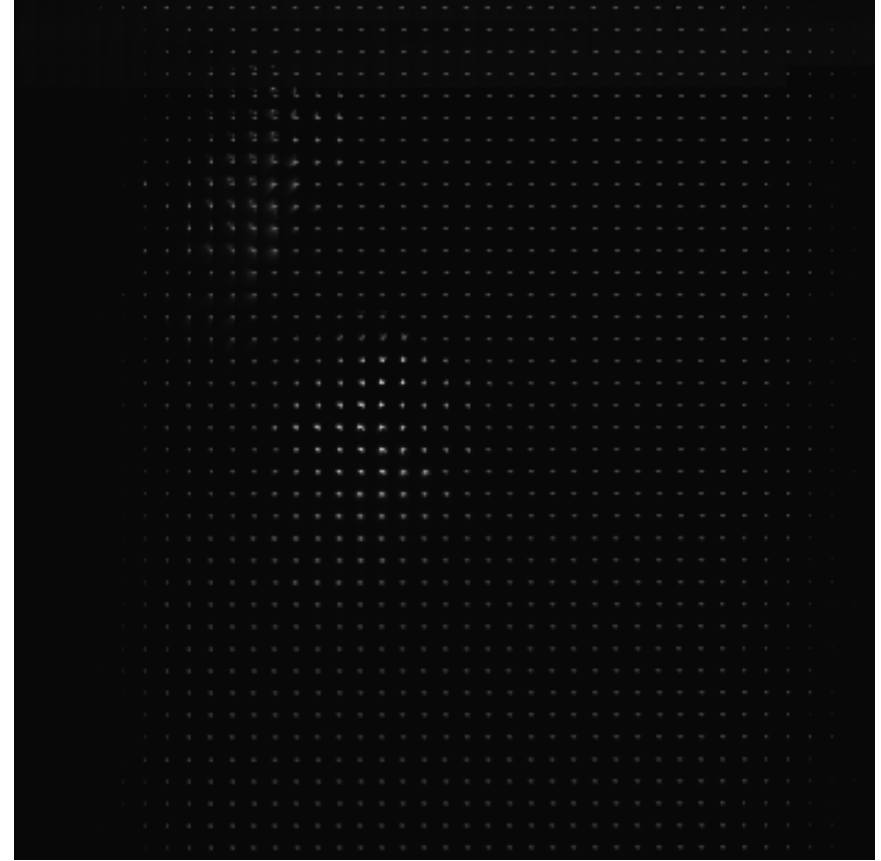


- Experiments with the first prototype

No defects



Two scattering defects



Light Field Methods – Deflection Map Processing



■ Experiments:

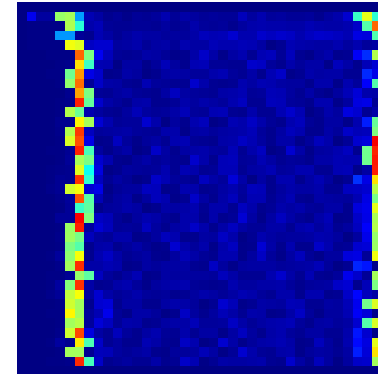
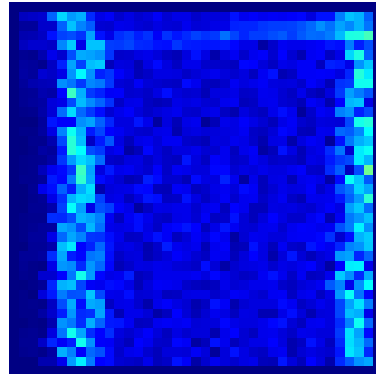
Test object: cylindrical plano-convex lens

Acquisition setup: early prototype of the laser deflection scanner

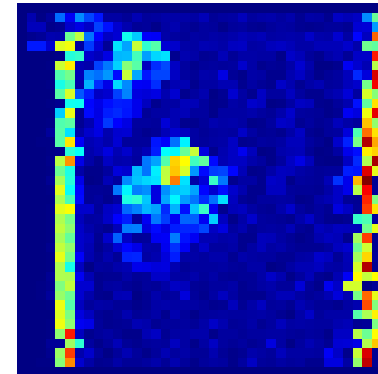
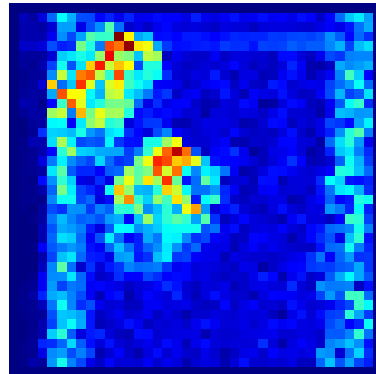
Earth mover's distance

Generalized Cramér-von Mises distance

Defect-free



Two scattering defects



Light Field Methods – Deflection Map Processing

■ Experiments:

■ Inferred defect size

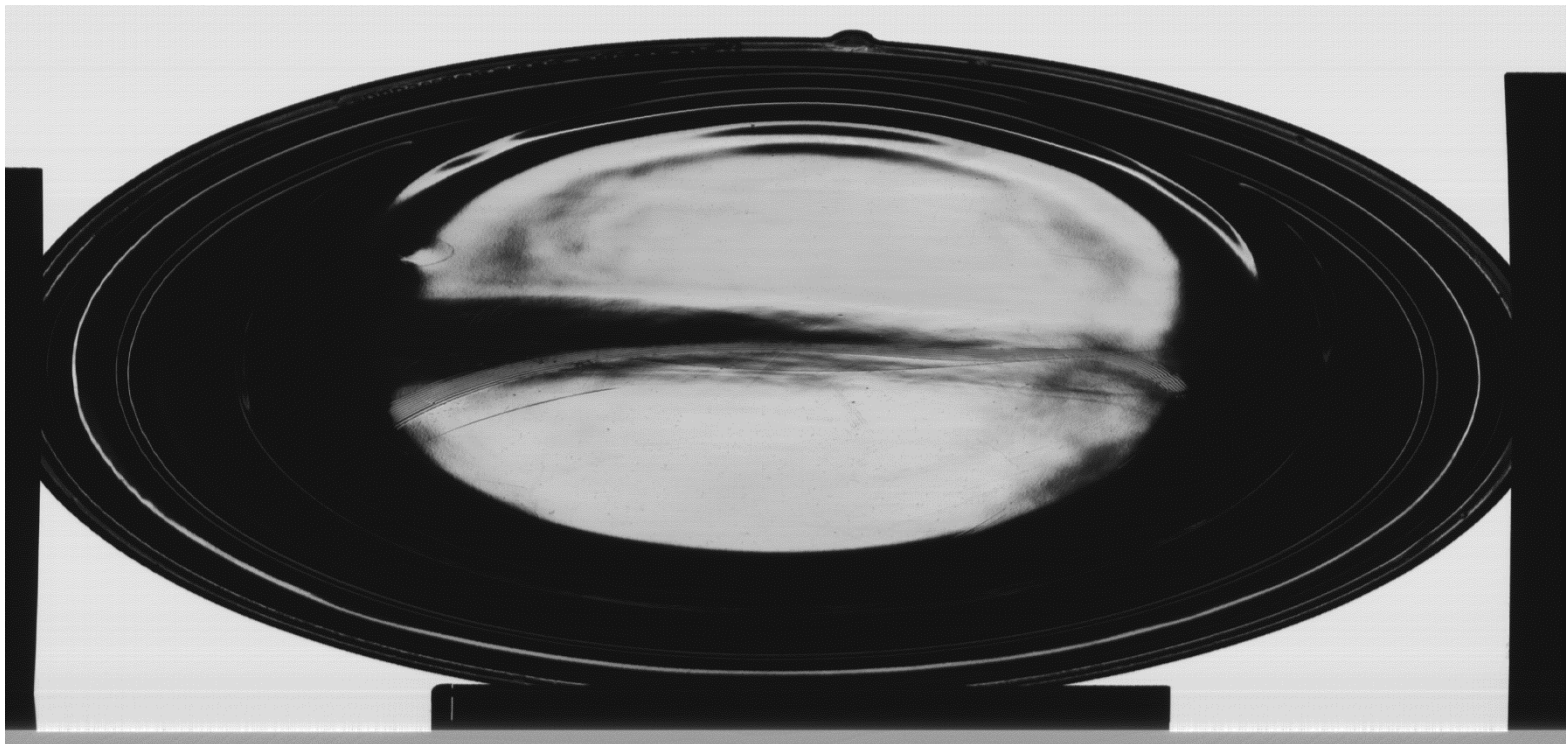
Defect	Upper left	Lower right
Manually measured size	2.8 mm x 2.8 mm	4 mm x 4 mm
EM-distance based estimation	4 mm x 4 mm	4.68 mm x 4.68 mm
CVM-distance based estimation	3 mm x 3 mm	4.34 mm x 4.34 mm

■ Signal-to-noise ratio and peak signal-to-noise ratio

	SNR	PSNR
EM-distance	15.3	28.3
CVM-distance	18.1	39.8

Light Field Methods – Deflection Map Processing

- Experiments with another prototype
 - Test object: Cover glass of a washing machine
 - Image obtained using conventional scanner:

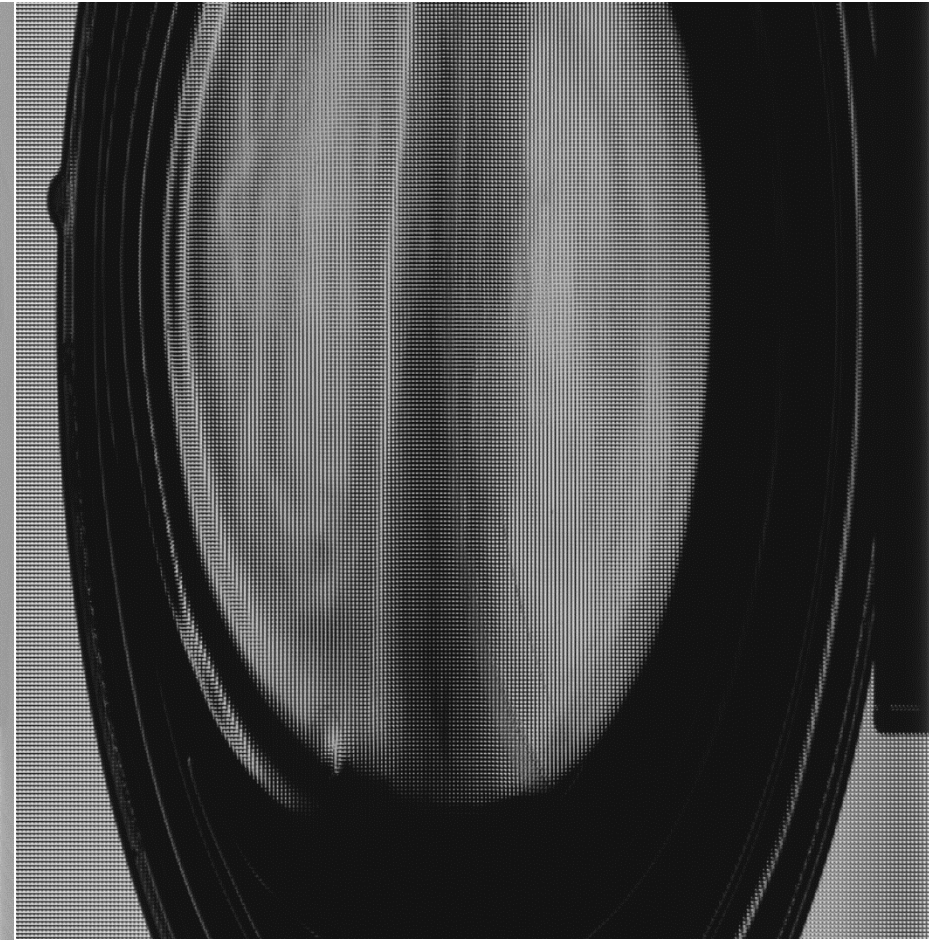


Light Field Methods – Deflection Map Processing

■ Image from conventional scanner:



■ Light field from laser deflection scanner:

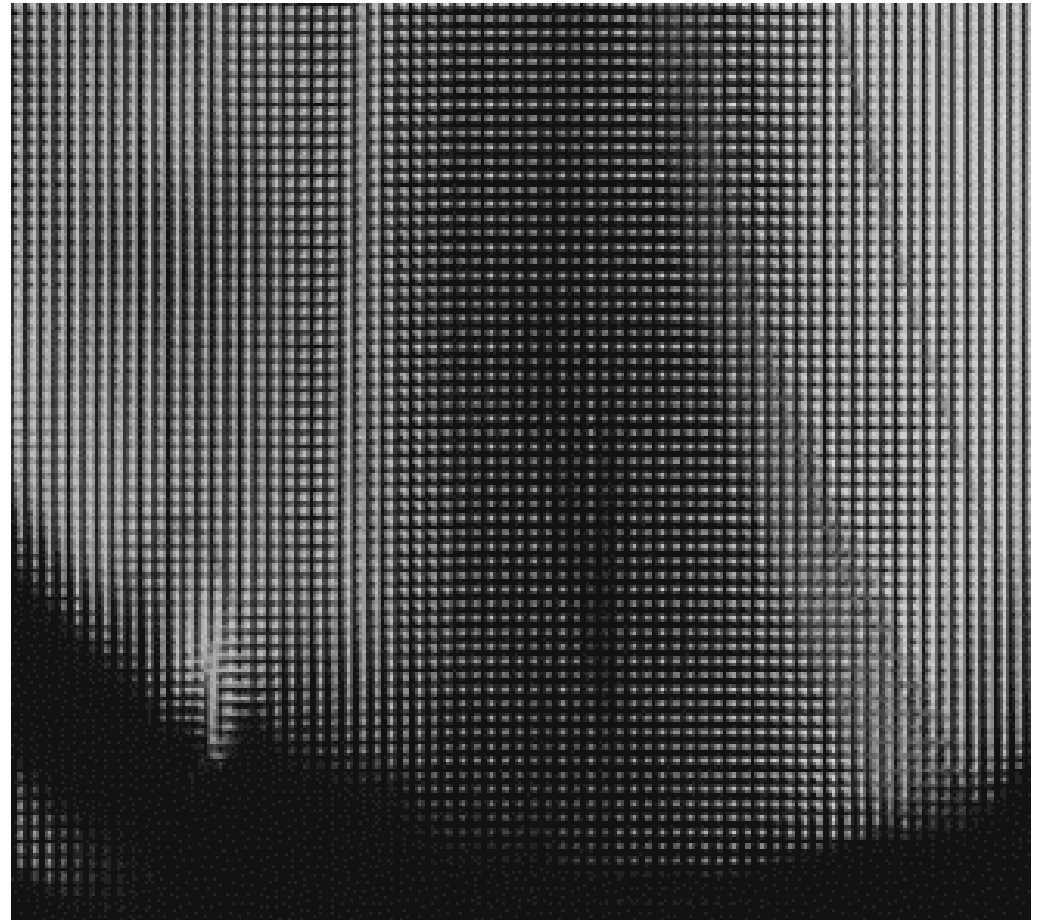


Light Field Methods – Deflection Map Processing

■ Image from conventional scanner:



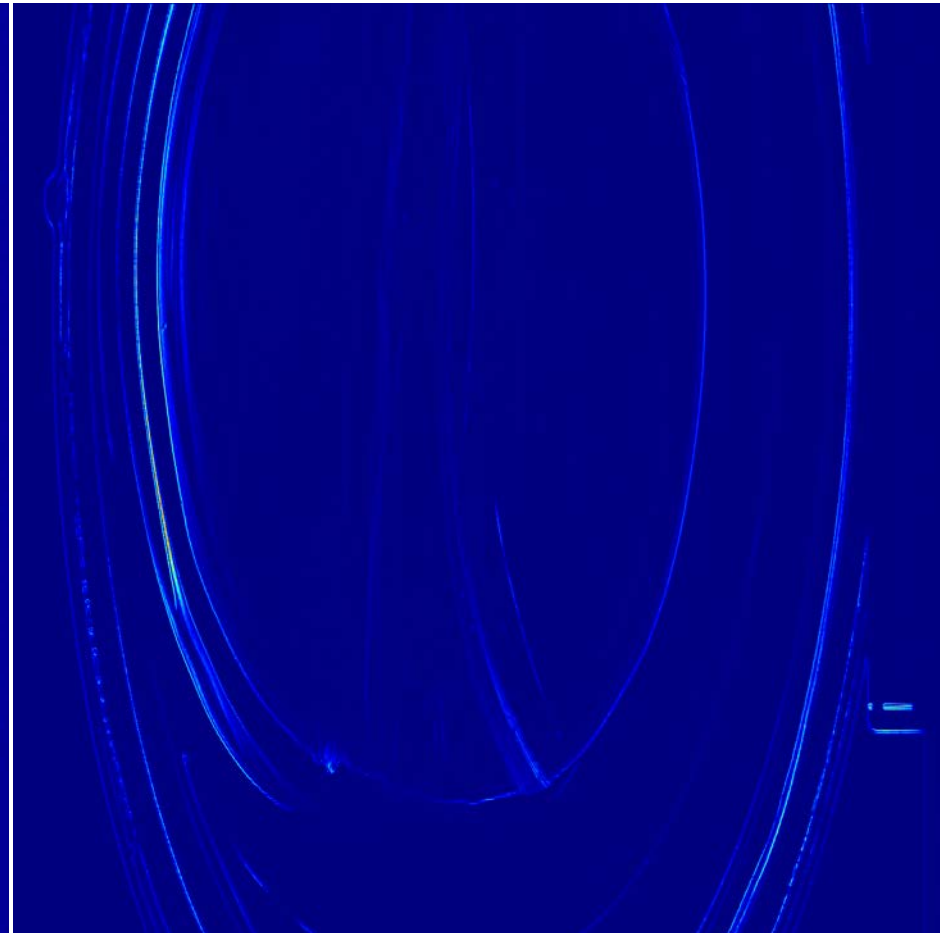
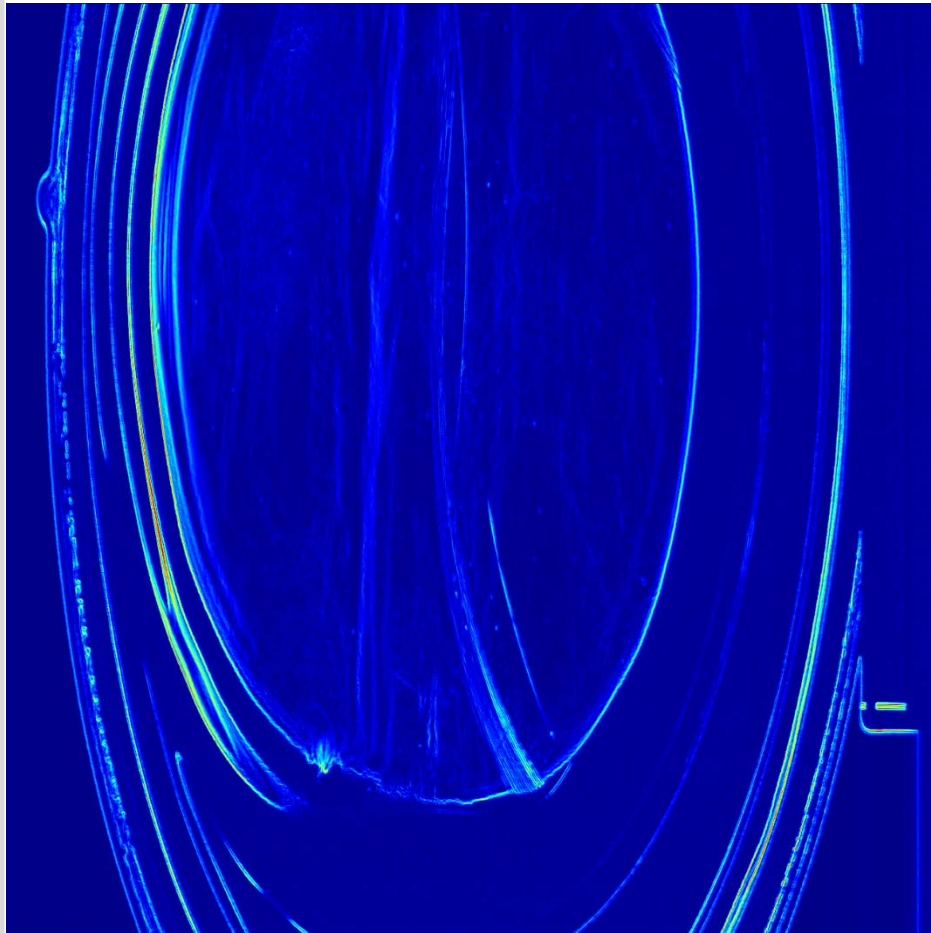
■ Light field from laser deflection scanner:



Light Field Methods – Deflection Map Processing

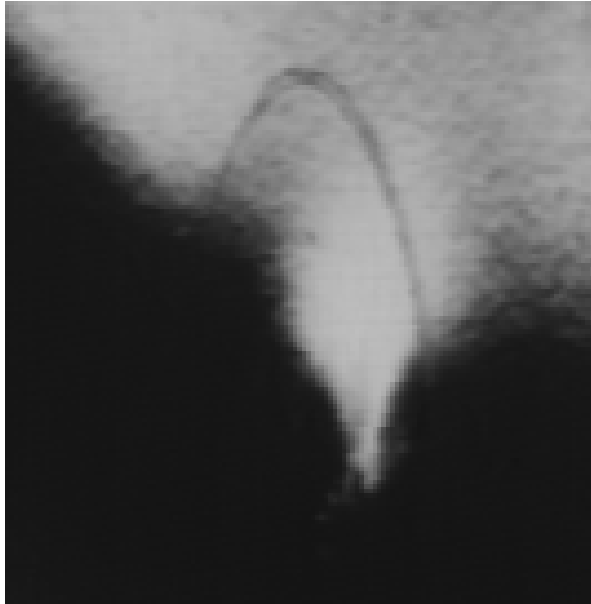
■ EM distance

■ GCVM distance

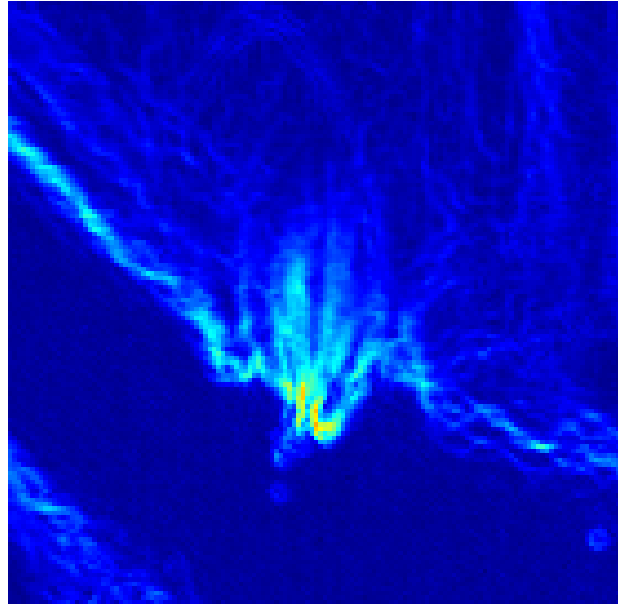


Light Field Methods – Deflection Map Processing

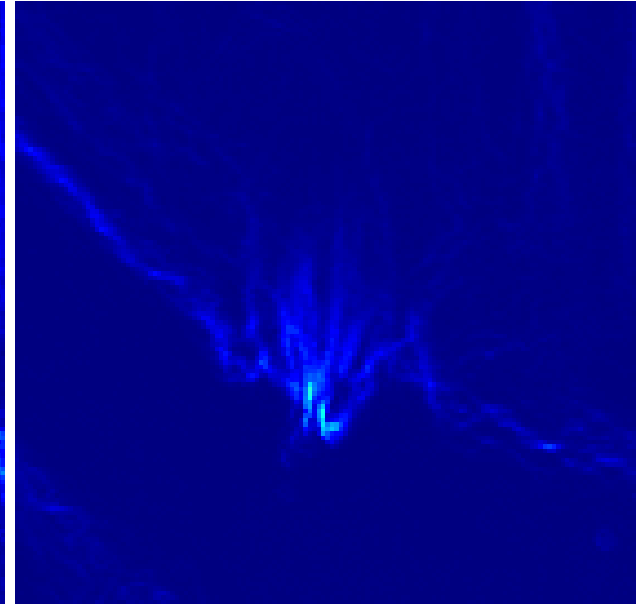
■ Image from conventional scanner



■ EM distance

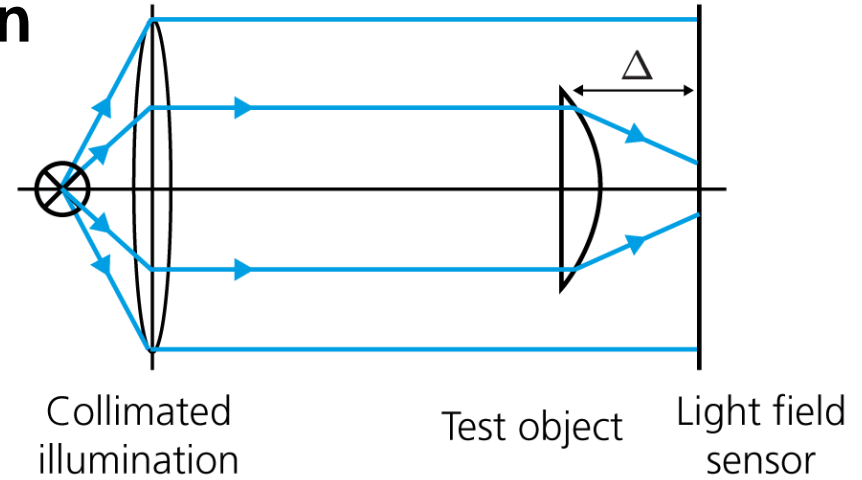


■ GCVM distance

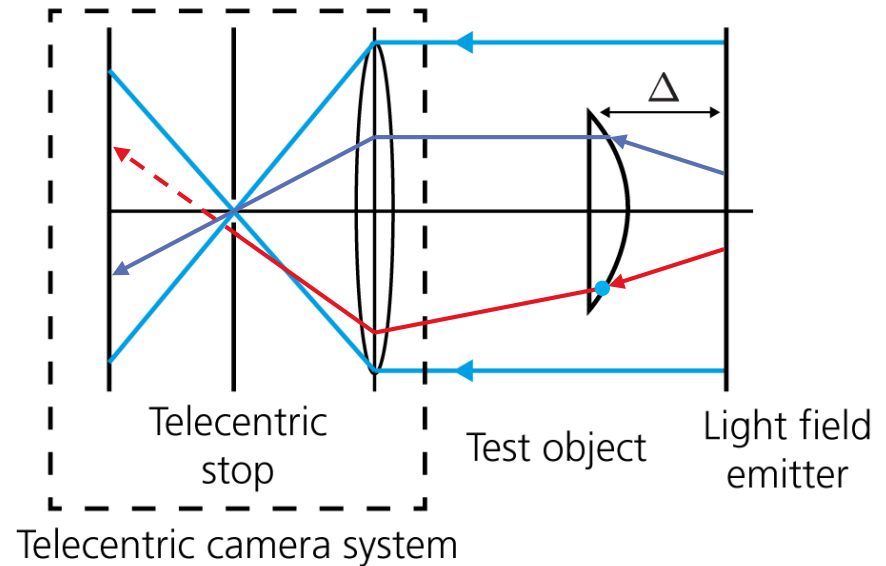


Light Field Methods - Inverse Light Field illumination

- Acquisition of a reference light field \mathcal{L} of a defect-free test object instance.



- Inspection of other test objects via illumination with \mathcal{L} and image acquisition using a telecentric camera.



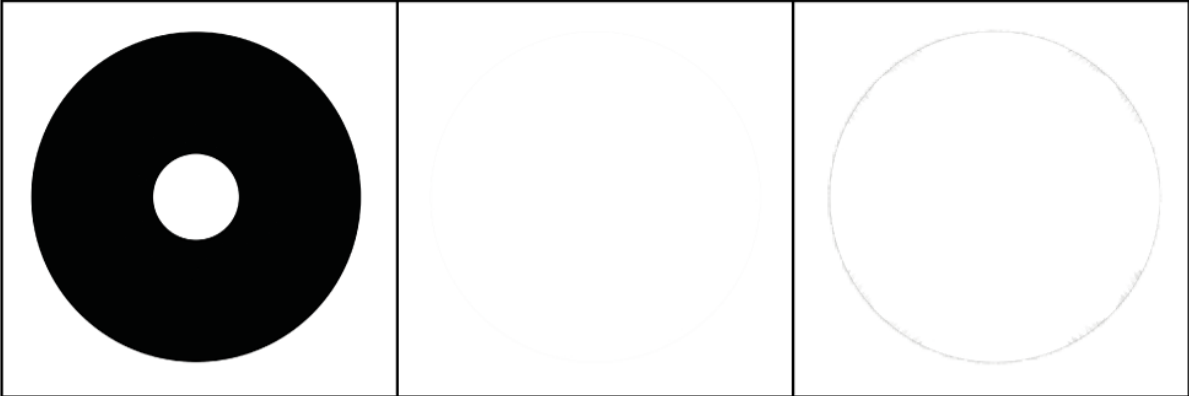
Simulation results

Collimated illumination

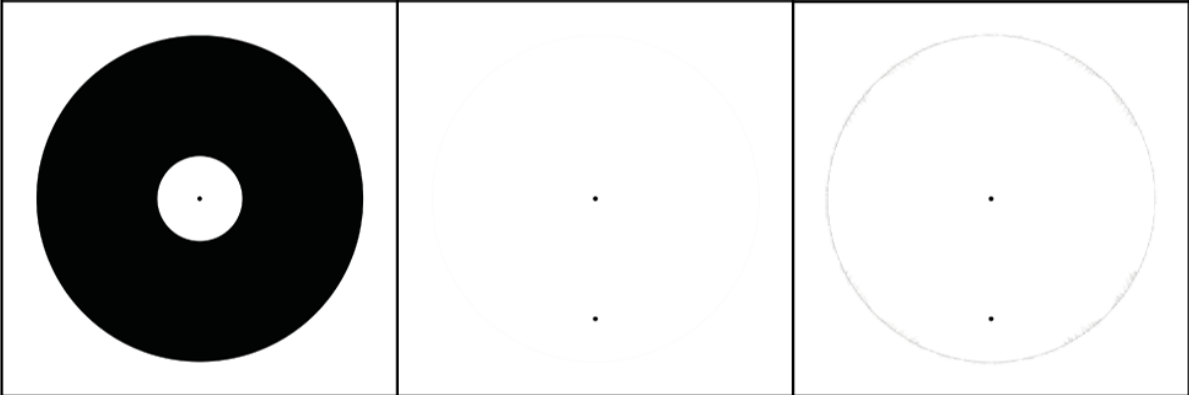
Area illumination

Inverse light field illumination

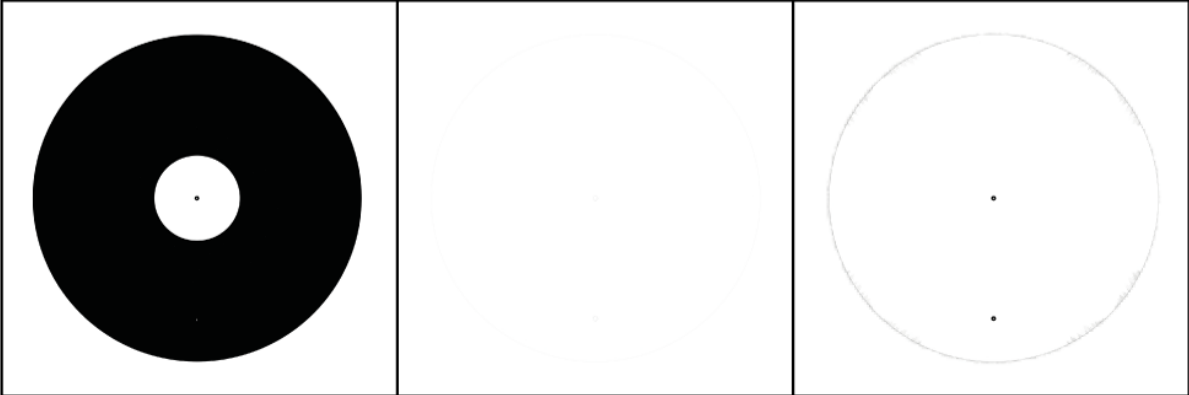
■ Defect-free test object



■ Test object with opaque inclusions



■ Test object with enclosed air bubbles



Summary & Outlook

- Automated visual inspection of transparent objects
 - High relevance for industry and academia
 - Consideration of the light's propagation direction leads to promising results
- Light field methods
 - Acquisition and processing of deflection maps
 - Laser deflection scanner
 - Proof of concept done with first prototypes
 - → **Industrial sensor currently under construction**
 - Processing methods and distance measures
 - 2D-Earth mover's distance, vector analysis, statistical methods
 - → **More experiments and comparison**
 - Inverse light field illumination
 - Successfully evaluated by simulation
 - **Practical evaluation**
 - Prototype built (is currently being calibrated)

Thank You for Your Attention!

Questions & Comments are Welcome!

Contact: johannes.meyer@kit.edu

- Picture / video credits:
 - Lens on slide 2:
Tamasflex - Own work, CC BY-SA 3.0, <https://commons.wikimedia.org/w/index.php?curid=17152418>
 - Automobile / windshield on slide 2:
Sofar 2 at English Wikipedia - Transferred from en.wikipedia to Commons., Public Domain,
<https://commons.wikimedia.org/w/index.php?curid=2214306>
 - Video on slide 3:
<http://victuslaser.com/resources/>
 - Cylindrical lens on slides 20, 21:
<http://www.dhresource.com/260x260s/f2-albu-g1-M00-5D-1B-rBVaGVYHGVKAPtAGAAAlhA2jC6s740.jpg/wholesale-plano-convex-cylindrical-lens-5.jpg>